

*15(2): 1-13, 2017; Article no.JSRR.34929 ISSN: 2320-0227*

# **Electrochemical, Spectrochemical and Quantum Chemical Studies on Dimedone as Corrosion Inhibitor for Copper in Acetonitrile**

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## *Authors' contributions*

*This work was carried out in collaboration between both authors. Author PC designed and analyzed the study as well as corrected the manuscript. Author SM conducted the experiments and outlined the manuscript. Both authors read and approved the final manuscript.*

## *Article Information*

DOI: 10.9734/JSRR/2017/34929 *Editor(s):* (1) Mahmoud Nasr, Sanitary Engineering Department, Faculty of Engineering, Alexandria University, Egypt. *Reviewers:* (1) Mieczyslaw Scendo, Jan Kochanowski University in Kielce, Poland. (2) Lebe Nnanna, Michael Okpara University of Agriculture, Nigeria. (3) Prakasha Shetty, Manipal Institute of Technology, Manipal University, India. Complete Peer review History: http://www.sciencedomain.org/review-history/20304

> *Received 20th June 2017 Accepted 25th July 2017 Published 1st August 2017*

*Original Research Article*

## **ABSTRACT**

The inhibition ability of 5,5-Dimethyl-1,3-cyclohexanedione (dimedone, DMD) for copper in acetonitrile at 25°C was investigated by potentiodynamic polarization and electrochemical impedance spectroscopy (EIS). Corrosion resistance increased with inhibitor concentration up to 93.68% inhibition efficiency at 3.00 mM, indicating that DMD molecules can cumulatively adsorb on the copper surface and finally form a protective film on copper-solution interface. This is also supported by the decreasing of copper oxidation in cyclic voltammogram. Polarization curves revealed that DMD is of mixed type inhibitor. The adsorption of DMD on copper surface obeys the Langmuir isotherm and the adsorption mechanism is of physisorption type. The standard energy of adsorption *(∆G<sup>o</sup> ads*) values was found in good agreement for both polarization and impedance to be -8.17 and -8.43 kJmol<sup>-1</sup> respectively. Fourier Transform Infrared spectroscopy (FT-IR) confirmed the interaction of copper with oxygen on DMD. The mole ratio method suggested that the complexation ratio of copper-DMD is 1:2. Scanning electron microscopy (SEM) of copper surface after immersion in DMD solution indicates the presence of a protective layer on the electrode surface. The frontier molecular orbital energy  $E_{HOMO}$  (highest occupied molecular orbital),  $E_{LUMO}$ 

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(lowest unoccupied molecular orbital) and the Mulliken charge distribution obtained from Quantum chemical calculations revealed (∆E) for DMD 0.2091 hartree, reflecting strong adsorption of the molecules on copper surface. The enhanced corrosion inhibition is possibly due to the compact film structure blocking electron transfer at the electrode surface.

*Keywords: Copper; corrosion inhibition; organic inhibitor; electrochemistry.*

## **1. INTRODUCTION**

Copper metal is widely used in a number of fields as a structural component especially in marine systems [1-3] due to its desirable physicochemical, aesthetic and mechanical properties However, the presence of CI makes it vulnerable to corrosion and makes corrosion inhibition economically important [3] due to the lost of partial or total replacement of equipment as well as structures and plant-repairing shutdowns.

The use of corrosion inhibitors is one of the most economical ways to reduce the corrosion rate, protect metal surfaces against corrosion and preserve industrial facilities [4]. Inorganic inhibitor is one of the simplest ways to improve the passivity of a metal by adding electropositive metal salts to the medium [5-7]. The inhibition is due to the reduction of electropositive ions followed by adsorption on the metal surface, which makes the metal more noble. However,<br>recently increasing concern toward increasing concern toward environmental and health consideration is likely to restrict inhibitor choices. A number of effective inhibitors such as chromate, phosphate, molybdate and nitrites will eventually be abandoned due to their toxicity [8]. Thus, there is still a need for testing and developing corrosion inhibitors that are effective and environmentally friendly in particular organic substitutes.

A number of organic compounds were found to have inhibitive properties including carboxylic acids, urea derivatives, amines, and other nitrogen containing compounds which can strongly adsorb onto the metal surface or react with the corrosion product on the surface to form a protective layer and provide a barrier to the dissolution of the metal in the electrolyte [9-14]. The efficiency of these organic corrosion inhibitors is related to the presence of polar functional groups including sulphur, nitrogen, oxygen and phosphorous atoms in their molecules as well as pi electrons especially in heterocyclic ring [15]. These polar groups are usually regarded as a reaction center for adsorption process. Consequently, in the light of corrosion inhibition, quinones with unpaired

electrons of oxygen pi-bonds and conjugated benzene rings are possible to facilitate protective inhibition. Only a few experimental data on the inhibition properties of simple and substituted quinones are available in the literature [16].

The goal of the present study is to present the remarkable inhibiting properties remarkable inhibiting properties of dimedone (DMD, Fig. 1), with greater<br>advantages of cost effectiveness and advantages of cost effectiveness and non-toxicity. Due to the fact that DMD as well as involving complexes are slightly soluble in water and there are quite a few corrosion studies in nonaqueous conditions with less effect from oxygen and proton, here EIS and potentiodynamic polarization were employed to evaluate corrosion rate of freshly polished copper and inhibition efficiencies of DMD as an inhibitor in acetonitrile. The copper surface was examined by SEM whereas the complexation between copper and DMD compounds was studied by CV, UV-Vis and FT-IR. The adsorption isotherm of DMD on copper surface and Quantum chemical parameters are also investigated to obtain more information about the mechanism of adsorption and corrosion inhibition of DMD on copper in acetonitrile.



**Fig. 1. Chemical structure of 5,5-Dimethyl-1,3 cyclohexanedione (DMD)**

## **2. MATERIALS AND METHODS**

## **2.1 Instruments**

The electrochemical measurements were carried out by Methrom AUTOLAB PGSTAT 100 with GPES software as well as by Methrom AUTOLAB PGSTAT 302N with NOVA software. Quantum chemical calculations were performed with the use of Gaussian 09 package. The molecular structures of DMD was fully geometrically optimized using the functional RB3LYP DFT formation with electron basis 6- 31G (d, p) for all atoms.

The Fourier Transform Infrared (FT- IR) spectrum was recorded with Perkin-Elmer FT-IR 783 model in KBr matrix at room temperature. The UV-Vis measurements were carried out by PerkinElmer Lambda 45 model and the surface morphology was analyzed by SEM of Quanta.

## **2.2 Electrochemical Cell Set-up**

All electrochemical techniques were carried out using a standard three-cell electrode system consisting of a high purity platinum wire as a counter electrode (CE), silver-silver chloride (Ag/AgCl) as a reference electrode (RE) and a working electrode (WE) which was 99.98% copper coupons for potentiodynamic polarization and EIS techniques whereas a glassy carbon electrode (GCE, 2 millimeter diameter) for CV technique. The reference electrode was serviced regularly by changing the internal filling solution with a saturated solution of super-purum KCl (99.999+%).

## **2.3 Electrode Preparation**

## **2.3.1 Electrochemical measurements**

For potentiodynamic polarization and EIS, Cu was mechanically polished with emery paper (#1000), degreased with acetone, dried at room temperature and then immersed immediately in the test solution. No attempt was made to remove the air-formed oxide film which may have formed on the metal surface prior to immersion. In the case of CV GCE was polished with alumina ( $0.05 \mu m$ ) water slurry on polishing cloth, rinsed well with distilled water and wiped several times with wetted soft tissue.

## **2.4 Sample Preparation**

## **2.4.1 Electrochemical measurement**

For potentiodynamic polarization and EIS, appropriate amount of DMD was dissolved and the volume made up with acetonitrile. In the case of supporting electrolyte for CV, 0.3880 g of TBAPF $<sub>6</sub>$  was dissolved with acetonitrile and the</sub> volume was made up to 100 mL.  $1.0 \times 10^{-3}$  M  $CuCl<sub>2</sub>·2H<sub>2</sub>O$  was prepared by dissolving 0.0170 g of  $CuCl<sub>2</sub>·2H<sub>2</sub>O$  and its volume was made up to 100 mL with 0.0100 M TBAPF $_6$  in acetonitrile. DMD 0.0140 g was dissolved and diluted to 100 mL to obtain  $1.0 \times 10^{-3}$  M solution. The mixture of Cu (II) and DMD solution was prepared by adding 0.0085 g of CuCl<sub>2</sub>.2H<sub>2</sub>O in 50 mL 1.0  $\times$ 10<sup>-3</sup> M DMD with 0.010 M TBAF in acetonitrile.

#### **2.4.2 Spectroscopic measurement**

For UV-Vis spectroscopy, 1.0  $\times$  10<sup>-3</sup> M CuCl<sub>2</sub>.2H<sub>2</sub>O was prepared by weighing  $0.0170$  g of  $CuCl<sub>2</sub>·2H<sub>2</sub>O$  and dissolved in acetonitrile<br>and the volume was made up to and the volume was made up to 100 mL. DMD 0.0140 g was prepared in the same way to obtain the concentration of 1.0  $\times$  10<sup>-3</sup> M.

For FTIR, copper-DMD complex solution was prepared by weighing 0.2800 g of DMD  $(2.0 \times 10^{-3} \text{ mol})$  and dissolved in 20.0 mL of methanol.  $CuCl<sub>2</sub>·2H<sub>2</sub>O$  0.1705 g  $(1.0 \times 10^{-3} \,\text{mol})$  in 15 mL of methanol was added and the solution was refluxed at 70°C for 5 hours. After filtering, the filtrate was left at room temperature for 1 month to obtain green crystals. Which were further isolated by suction filtration, washed with acetone and dried in a vacuum desiccator. The sample obtained was ground to reduce the particle size to less than 5 mm in diameter. A small amount of powder sample (about 0.1-2% of the KBr amount, or just enough to cover the tip of spatula) was mixed with the KBr powder, subsequently ground for 3-5 min and then pressed to form a thin and transparent pellet.

## **2.5 Procedure**

## **2.5.1 Electrochemical measurement**

In polarization measurement, 50 mL of the test solution was pipetted into the 100 mL cell. The measurements were made after allowing the electrode to achieve the steady state potential under open-circuit condition at room temperature. The nature of inhibitor was interpreted via polarization curves with a scan rate of 0.5 mV/s on freshly-prepared copper electrodes. Inhibition efficiencies were then evaluated (*vide infra*) from corrosion current densities  $(i_{corr})$  obtained by Tafel extrapolation method.

Impedance measurement was carried out in the same way as polarization measurement. Impedance spectra were obtained in the frequency range of 0.1 Hz to 150 kHz with perturbation amplitude of 10 mV. Inhibition efficiencies were evaluated from charge transfer resistance  $(R_{\text{ct}})$ .

CV studies were carried out in a glass cell with a capacity of 100 ml. 50 mL mixture of Cu (II) and DMD solution was pipetted into the cell and

cyclic voltammograms were recorded in the potential range of -1.8 to 1.8 V with scan rate of 100mV/s.

#### **2.5.2 Spectroscopic measurements**

#### *2.5.2.1 UV-Vis spectroscopy*

In the mole ratio method, different aliquots of DMD solution were added in 3.0 mL of 1.0  $\times$  10<sup>-3</sup> M copper (II) solution in order to get various metal ligand ratios ranging from 1:0.8 to 1:4.0. The absorbance was  $reordered$  at  $\lambda$ max 246 nm and temperature maintained at 25°C. ratio method, different aliquots of<br>lution were added in<br>0 × 10<sup>-3</sup> M copper (II) solution in<br>various metal ligand ratios ranging<br>to 1:4.0. The absorbance was<br> $\lambda$ max 246 nm and temperature

#### *2.5.2.2 FTIR*

The chemical structure of the sample was determined by using absorption FTIR The chemical structure of the sample was<br>determined by using absorption FTIR<br>spectroscopy at a resolution of 4 cm<sup>-1</sup>. 16 additive scans were carried out between 4000 to 400 wave numbers.

## **2.5.3 Microscopy by SEM**

After preparation, 1.0  $\times$  1.0 cm<sup>2</sup> Cu electrodes were immersed in the test solution for 6 h, dried at room temperature and then investigated by SEM. test

#### **2.5.4 Quantum chemical calculations calculations**

Quantum chemical calculations using density functional theory (DFT) methods were applied to give values of the highest occupied molecular Quantum chemical calculations using density<br>functional theory (DFT) methods were applied to<br>give values of the highest occupied molecular<br>orbital (E<sub>HOMO</sub>), lowest unoccupied molecular orbital (E<sub>LUMO</sub>), dipole moment (D) and Mulliken atomic charge distribution of the DMD molecule,

forming complex with metal. which are useful in explaining electron density in

#### **3. RESULTS AND DISCUSSION SSION**

## **3.1 Cyclic Voltammetry and Mole Ratio**

mograms were recorded in the which are useful in explaining electron density in equilibration of the which are useful in explaining of the spectroscopy<br>
3. RESULTS AND DISCUSSION<br>
3. RESULTS AND DISCUSSION<br>
2. RESULTS AND The preliminary information about how DMD can influence the corrosion process of copper is pointed by its electrochemical behavior. The redox behavior of Cu (II) in copper (II) The preliminary information about how DMD can<br>influence the corrosion process of copper is<br>pointed by its electrochemical behavior.<br>The redox behavior of Cu (II) in copper (II)<br>chloride in 0.01 M TBAPF<sub>6</sub> in acetonitrile by cyclic voltammetry on glassy carbon electrode at 25°C confirms the formation of Cu (II) DMD complex (Fig. 2). The shift of both reduction peaks of Cu (II) to more negative reveals less electron density which makes accepting electron more difficult. On the other ha oxidation peaks shift to more positive which also indicates less possibilities in transferring electron due to complex formation. Similar behaviors are found for the case of peaks from DMD, especially oxidation. The complexation ratio of copper-DMD was also found to be 1:2 by mole ratio method. try (II) reduction electron accepting hands, also indicates less possibilities in transferring<br>electron due to complex formation. Similar<br>behaviors are found for the case of peaks from<br>DMD, especially oxidation. The complexation<br>ratio of copper-DMD was also found t

## **3.2 Potentiodynamic Polarization**

Fig. 3 illustrates the potentiodynamic polarization curves of copper in acetonitrile with and without DMD from which relevant parameters are obtained (Table 1) namely corrosion potential  $(E_{corr})$ , anodic and cathodic Tafel slopes  $(\beta_a, \beta_c)$ , polarization resistance  $(R_p)$ , corrosion current polarization resistance (R<sub>p</sub>), corrosion current<br>density (j<sub>corr</sub>), corrosion rate (v<sub>corr</sub>), surface coverage degree  $(\theta)$  and corrosion inhibition efficiency (IE%).





The presence of DMD causes small fluctuations of  $E_{corr}$  between -0.24 V and of  $E_{\text{corr}}$  between -0.24 V and<br>-0.30 V and the change of β<sub>a</sub> and -β<sub>c</sub>, indicating that DMD acts as a mixed-type corrosion inhibitor which suppresses both anodic and cathodic reaction simultaneously [17]. This suppression of the corrosion process<br>possibly results from adsorbed DMD possibly results molecules on copper surface which bloc inhibitor which suppresses both anodic<br>nodic reaction simultaneously [17].<br>pression of the corrosion process<br>results from adsorbed DMD<br>on copper surface which blocks corrosion mechanism. Furthermore, corrosion mechanism. Furthermore,<br>by increasing DMD concentration, j<sub>corr</sub>, v<sub>corr</sub> greatly decrease and the IE% calculated from j<sub>corr</sub> (Eq. (3)) increases. Also,  $\theta$  increases with DMD concentration. At low DMD concentrations in solution, it can be concluded that they obstruct the corrosion by merely preventing the reaction sites on copper surface. solution, it can be concluded<br>t the corrosion by merely<br>tion sites on copper surface.



**Fig. 3. Potentiodynamic polarization curves for copper in acetonitrile with DMD at various concentrations at 25°C and 0.5 mVs-1 scan rate**





The  $j_{corr}$  of copper was determined using the relation (1) and the  $v_{corr}$  and IE% with equations (2) and (3):

$$
i_{corr} = \frac{\beta_a \beta_c}{2.303 \times R_p \times (\beta_a + \beta_c)}
$$
 (1)

where 2.303 is the conversion factor

$$
v_{\text{corr}} = \mu_{eq} K_p \frac{j_{corr}}{\rho} \tag{2}
$$

where  $\mu_{eq}$  is equivalent weight of copper (31.78 amu),  $K_{p}$  is a proportionality constant (3.27  $\times$  10<sup>-3</sup>) and  $\rho$  is copper density (8.96 g/cm<sup>3</sup>)

$$
IE\% = \frac{j_{corr}(uninh) - j_{corr}(inh)}{j_{corr}(uninh)} \times 100\tag{3}
$$

where  $j_{corr}(inh)$  and  $j_{corr}(uninh)$  are the corrosion current densities for copper electrode in acetonitrile with and without DMD respectively.

## **3.3 EIS Measurement**

The influence of DMD on the adsorption process and corrosion inhibition on copper surface can be partially obtained by EIS. The Nyquist diagram for copper in acetonitrile solution, without and in the presence of different concentrations of DMD, were similar in shape (Fig. 4) of a single semicircle which indicates the corrosion reaction is controlled by the charge transfer process [18-20].

Typical Bode EIS plots obtained for copper in acetonitrile, without and in the presence of different concentrations of DMD are shown in Fig. 5. It can be seen that the impedance values of the copper are lower at high frequency, increases with decreasing frequency, and slightly increased at the lowest frequency. By increasing DMD concentration, the impedance of copper at low frequencies attained higher values. This demonstrates that the copper surface is more passivated due to the adsorption of DMD molecules on the Cu surface [21].

With the analysis of impedance data using the equivalent circuit (EC) as shown in Fig. 6, charge transfer resistance  $(R_{ct})$  and double-layer capacitance  $(C_{\text{dl}})$  were obtained (Table 2).



**Fig. 4. Nyquist plots copper in acetonitrile solution containing various concentrations of DMD at 25°C**

$C_{\text{inh}}/mM$	$R_e/\Omega$ cm <sup>2</sup>	$R_{\rm ct}/k\Omega$ cm <sup>2</sup>	$C_{dl}/pF$	θ	IE%*
0.00	257.60	63.71	72.40	-	$\overline{\phantom{0}}$
0.25	262.10	88.18	41.50	0.38	38.41
0.50	245.62	88.74	38.00	0.39	39.29
1.00	258.00	104.54	28.00	0.64	64.09
2.00	250.32	117.84	20.00	0.84	84.95
3.00	261.49	123.40	17.80	0.94	93.68

**Table 2. Electrochemical impedance parameters for copper in acetonitrile solution in the**<br>
absence and presence of DMD at different concentrations at 25°C<br>  $\frac{1}{2}$   $\frac{1}{2}$   $\frac{1}{2}$   $\frac{1}{2}$   $\frac{1}{2}$   $\frac{1}{2}$   $\frac{$ ctrochemical impedance parameters for copper in acetonitrile sol<br>absence and presence of DMD at different concentrations at 25°C



**Fig. 5. Bode plots copper in acetonitrile solution containing various concentrations of DMD at 25°C**





It is apparent that the  $(R<sub>ct</sub>)$  values of copper in It is apparent that the  $(R_{ct})$  values of copper in acetonitrile solution significantly increased with increasing amount of DMD, indicating that the presence of DMD improved copper corrosion inhibition. Additionally, the decrease in C<sub>dl</sub> values caused both the decrease in the dielectric constant and the increase of the double layer thickness, also supporting the adsorption of DMD on the copper/solution interface [21]. Finally, progressive covering of copper surface by DMD leads to the maximum inhibition efficiency of 93.68% with DMD at the 3.0 mM (Table 2), in good agreement with polarization results. With the concentration over 3.00 mM, %IE was only slightly increased which was possibly due to surface saturation. The  $R_{ct}$  and  $C_{dl}$  are calculated from Eq. (4): sed both the decrease in the dielectric stant and the increase of the double layer cness, also supporting the adsorption of DMD the copper/solution interface [21]. Finally, pressive covering of copper surface by DMD is to

$$
f(-Z^{\prime\prime}\_\text{max}) = \frac{1}{2\pi c_{dl}R_{ct}}\tag{4}
$$

where (-Z"<sub>max</sub>) is the maximum imaginary component of the impedance, and %IE is calculated from  $R_{ct}$  data by Eq. (5)

$$
IE\% = \frac{R_{ct} - R_{ct}^0}{R_{ct}^0} \times 100
$$
 (5)

where  $R_{ct}$  and  $R_{ct}^{0}$  are the charge transfer resistance with and without DMD, respectively.

#### **3.4 Adsorption Isotherm**

The adsorption isotherm is an effective way to explain the adsorption mechanism of the inhibitors [22]. A number of adsorption isotherms were tested for DMD adsorption on copper, including Freundlich, Temkin, Flory-Huggins and Langmuir. Langmuir isotherm was found to provide the best description for the adsorption behaviour of DMD as follows [11]:

$$
\frac{c_{inh}}{\theta} = \frac{1}{\kappa_{ads}} + C_{inh} \tag{6}
$$

where  $C_{inh}$  is the inhibitor concentration,  $K_{ads}$  the equilibrium constant for adsorption process and  $\theta$  the surface coverage degree by inhibitor molecules and the metal surface.

The surface coverage degree  $\theta$  (Table 1 and Table 2) was calculated by IE%/100 [19] from

 $\overline{4}$ 

both impedance and polarization measurements with good agreement of linear relationships between C/ $\theta$  and C as shown in Fig. 7. Linear correlation coefficients  $(R^2)$  of 0.9652 and 0.9780 from potentiodynamic polarization and EIS techniques respectively, indicating that the adsorption of DMD on copper surface at 25°C obeys the Langmuir adsorption isotherm [11].

*Kads* can then be calculated from the intercepts to be 1.38 and 1.54 mM from potentiodynamic polarization and EIS respectively. K<sub>ads</sub> is related to standard energy of adsorption *(∆G<sup>o</sup> ads*) by the equation [19]:

$$
\Delta G^{\circ}_{ads} = -RTIn(19.147K_{ads})
$$
 (7)

where 19.147 is the concentration in M of acetonitrile. Calculated *∆G<sup>o</sup>*  $\Delta G^o_{ads}$ from impedance and polarization data was -8.43 and -8.17 kJmol<sup>-1</sup> respectively. *ads* of  $-20$  kJmol<sup>-1</sup> or lower indicates physisorption whereas that about -40 kJ mol $^{-1}$  involves charge sharing or a transfer from the inhibitor molecules to the metal surface to form a coordinate type of bond (chemisorption) [23]. Hence the adsorption of DMD compounds is of physisorption type. The negative values of *∆G<sup>o</sup> ads* reveal the spontaneity of adsorption process and stability of the adsorbed layer on the copper surface.



**(a)**



**Fig. 7. Langmuir adsorption isotherm by impedance (a) and polarization (b) measurement of DMD on copper surface in acetonitrile at 25°C**

## **3.5 Fourier Transform Infrared Spectroscopy (FT-IR)**

Fig. 8 shows FT-IR spectrum of solid DMD on KBr pellet. The spectrum shows a peak bands of C-H stretching at 2956.09  $cm^{-1}$ , C=O stretching at 1733.82  $\text{cm}^{-1}$  and C-H bending at 1411.74  $\text{cm}^{-1}$ <br><sup>1</sup>. The same obaracteristic bands appeared for . The same characteristic bands appeared for

Cu (II) DMD complex with strong C=O stretching modification (Fig. 9 and Table 3): C=O stretching had disappeared due to the complex formation between C=O and Cu, C-H stretching at 2961.00  $cm^{-1}$  and C-H bending at 1421.66  $cm^{-1}$  [24]. The shift indicates the *change of* electron cloud density due to the coordination with Cu (II) [25].



**Fig. 8. IR spectrum of DMD**



**Fig. 9. IR spectrum of DMD and CuCl<sub>2</sub>**2H<sub>2</sub>O





## **3.6 Morphological Studies of Copper Surface**

Copper surface was characterized by SEM whose results without DMD shown in Fig. 10 (a) indicate smooth surface with certain scratches on the bare copper surface caused by polishing in the electrode cleaning process. Similarly, copper surface after removing the layer of DMD (Fig. 10 (b)) shows the same characteristics as that in the case of the bare copper. With DMD, a protective layer is shown (Fig. 10 (c)) in good accordance with the results obtained from potentiodynamic measurements and EIS.

#### **3.7 Quantum Chemical Calculations**

To investigate the effect of molecular structure on inhibition mechanism, quantum chemical calculations were performed for neutral species. The geometry of DMD compound was determined by optimizing all geometrical variables without any symmetry constraints to obtain the result shown in Fig. 11(c). 11(c). Certain quantum chemical parameters are related to the interactions between the inhibitor and the copper surface including E<sub>HOMO</sub>, E<sub>LOMO</sub> and dipole moment (D).  $E_{HOMO}$  is associated with the capacity of a molecule to donate electrons and (Fig. 10 (c)) in good accordance with the results<br>obtained from potentiodynamic measurements<br>and EIS.<br>**3.7 Quantum Chemical Calculations**<br>To investigate the effect of molecular structure<br>on inhibition mechanism, quantum ch adsorption hence the inhibition efficiency, which also indicates the disposition of the molecule to adsorption hence the inhibition efficiency, which<br>also indicates the disposition of the molecule to<br>donate orbital electrons to an appropriate acceptor with empty molecular orbitals [26]. In contrast,  $E_{LUMO}$  indicates the ability of the molecule to accept electrons. The lower the value of  $E_{LUMO}$ , the more probable is the molecule to accept electrons. Low absolute value of the energy band gap ( $E_{HOMO}$  -  $E_{LUMO}$ ) renders good inhibition efficiencies because it means lower energy to remove an electron from the highest occupied orbital [26]. the increase in the value of  $E_{HOMO}$  can facilitate mpty molecular orbitals [26]. In<br>indicates the ability of the<br>cept electrons. The lower the<br>, the more probable is the<br>pt electrons. Low absolute value<br>nd gap ( $E_{HOMO}$  -  $E_{LUMO}$ ) renders because it means<br>electron from the<br>gh HOMO (-0.2449

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contain stream contrast, E<sub>LUMO</sub> indicates the DMD was found to have high HOMO (-0.2449) hartree (Table 4)) with the preferred active sites for an electronic attack and the favourite sites for interaction with the metal surface located at 1,3 cyclohehadione in the molecule (Fig. 11 (a)) whereas its  $E_{LUMO}$  is low (-0.03583 hartree). Additionally, low energy gap of 0.2091 hartree support DMD high inhibitory performance. The dipole moment of the molecule is also calculated due to the fact that it is influenced by the molecular structure and is expected to play a role in the adsorption process [26]. High D of DMD (3.6935, Table 4) reveals the favor of the molecule to accumulate on the surface layer and in turn reduce the rate of electrochemical reaction [27]. hartree (Table 4)) with the preferred active sites<br>for an electronic attack and the favourite sites for<br>interaction with the metal surface located at 1,3cyclohehadione in the molecule (Fig. 11 (a))<br>whereas its  $E_{LUMO}$  is low (-0.03583 hartree).<br>Additionally, low energy gap of 0.2091 hartree<br>support DMD high inhibitory performance. The<br>dipole moment of the molecule is als



#### **Table 4. Quantum chemical parameters of DMD**

**Fig. 10. SEM micrographs of (a) bare copper surface (b) copper surface after removing the layer of DMD and (c) copper surface in the presence of 3.00 mM DMD after 6 h**



Fig. 11. (a) E<sub>HOMO</sub>, (b) E<sub>LUMO</sub>, and (c) Mulliken atomic charge distribution of DMD molecule **calculated by RB3LYP DFT method**

The Mulliken atomic charge distribution calculated using the DFT method is presented in Fig. 11 (c). Oxygen and some carbon atoms have higher charge densities so they are generally the sites where electrophiles attack. Therefore, O and C atoms were active centers with the ability to form a protective film by physical adsorption with copper surface. In addition, the HOMO (Fig. 11 (a)) was mainly distributed on 1,3-cyclohexanedione, the framework of DMD, which therefore probably the primary site in forming a protective film. It could be deduced on the above discussion that DMD, apart from existing in the anionic form which can interact with copper surface by electrostatic attraction, may also interact with the copper surface via oxygen and carbon atoms, forming an effective protective layer on the copper surface thus retarding further corrosion of the metal in acetonitrile.

#### **4. CONCLUSION**

Inhibition efficiency of DMD towards copper corrosion in acetonitrile solution was determined by electrochemical techniques including polarization and impedance measurements to<br>obtain 88.37 and 93.68% respectively. obtain 88.37 and 93.68% respectively. Potentiodynamic polarization revealed that DMD is a mixed-type corrosion inhibitor with efficiency which increases with concentration. Protection afforded by DMD is due to its physical adsorption obeying Langmuir isotherm. The adsorption layers and corresponding complexes formed by DMD are further confirmed by the results from CV, SEM, UV-Vis and FTIR analysis. From calculated standard energy of adsorption and quantum chemical calculations, the driving force for the formation of protective film could be the physisorption via the oxygen and carbon atoms.

## **COMPETING INTERESTS**

Authors have declared that no competing interests exist.

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